

PTO-1449

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Information Disclosure Citation
In an Application

Application No.

10/849,192

Docket Number

074038.0127

Applicant(s)

Mohammed N. Islam et al.

Group Art Unit

Filing Date

2872

August 27, 2003

U.S. PATENT DOCUMENTS

	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
A						
B						
C						
D						
E						
F						
G						
H						
I						
J						
K						
L						
M						

FOREIGN PATENT DOCUMENTS

	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
N						YES
O						
P						

NON-PATENT DOCUMENTS

	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
78 Q	Y. Chen, et al., "Modeling and Control of Nanomirrors for EUV Maskless Lithography," Technical Proc. Int. Conf. Modeling and Simulations of Microsystems, San Diego, CA, 3 pages	March 2000
79 R	W.R. Wlezniewski et al., "Mechanical Light Modulator Fabricated on a Silicon Chip using Simox Technology," pp. 1027-1030	December 1996
S		
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EXAMINER

J. Alyngula

DATE CONSIDERED

4 AUGUST 2004

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

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Information Disclosure Citation
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Applicant(s)

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Group Art Unit

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V	—	—
W	—	—

EXAMINER

John Gulec

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